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BaZrS₃ Chalcogenide Perovskite Thin Film Grown by Reactive Sputtering

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Outline

➤ Motivation



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Outline

- Motivation
- Co-sputtering



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Outline

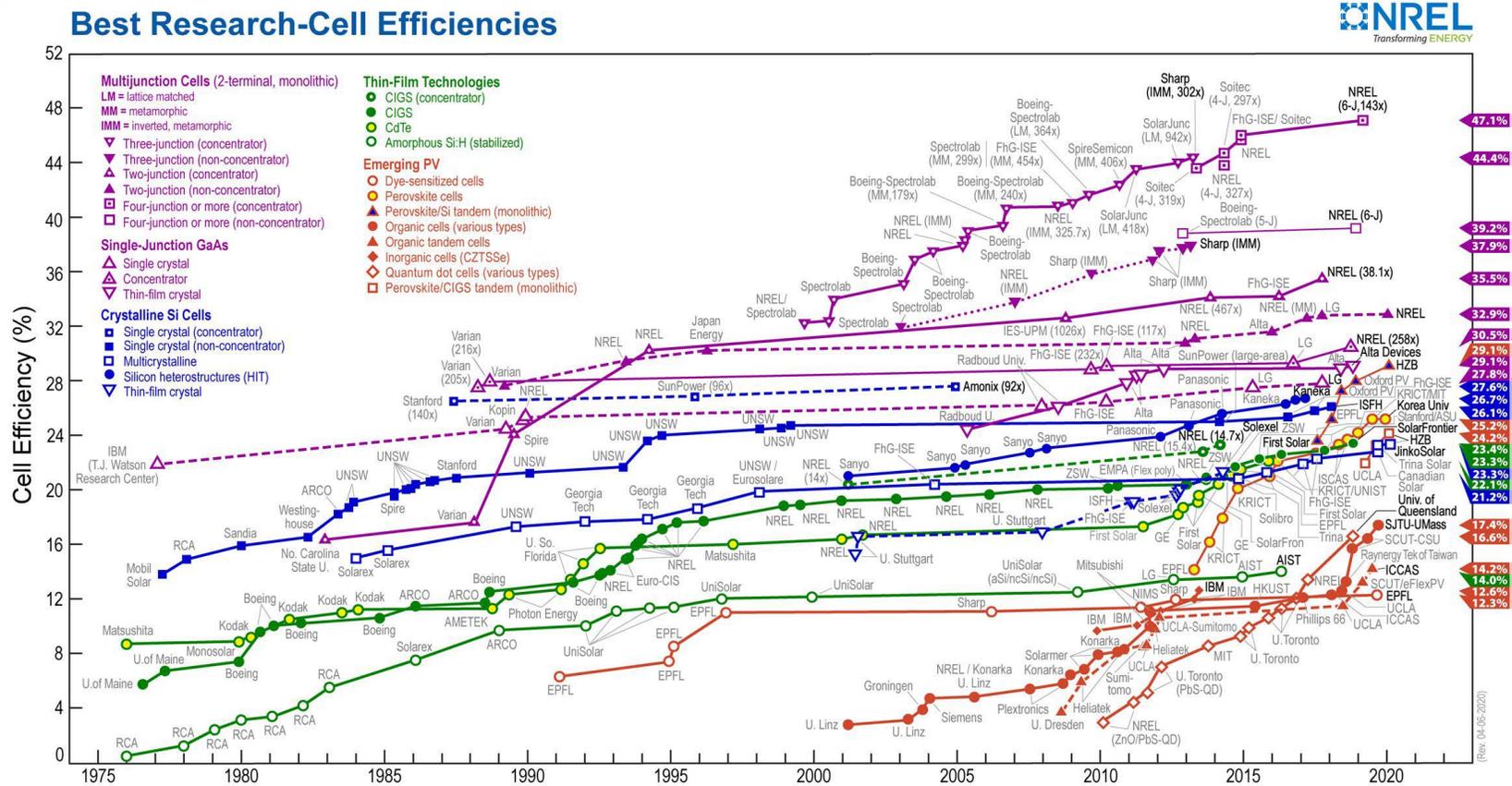
- Motivation
- Co-sputtering
- Sequential sputtering

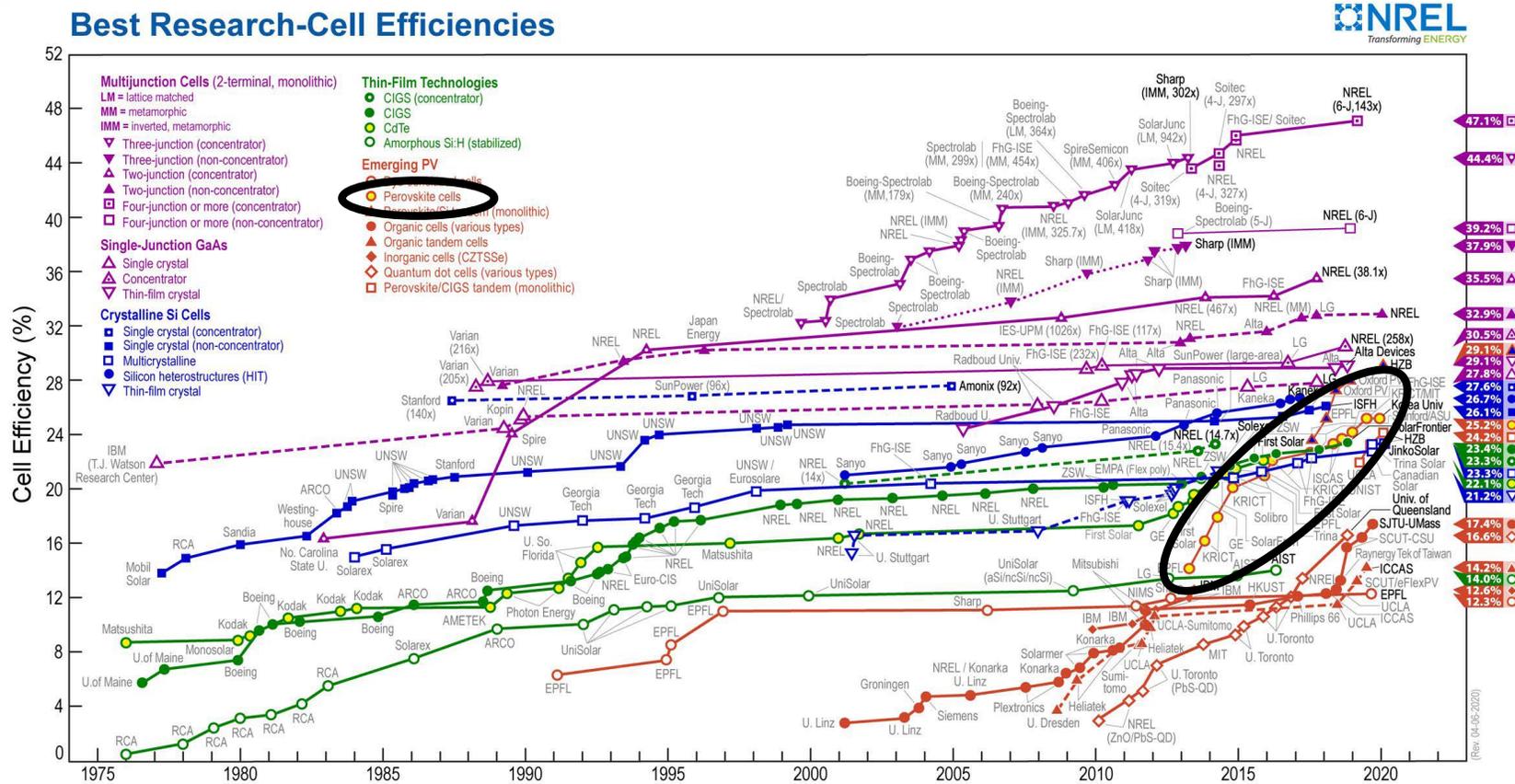


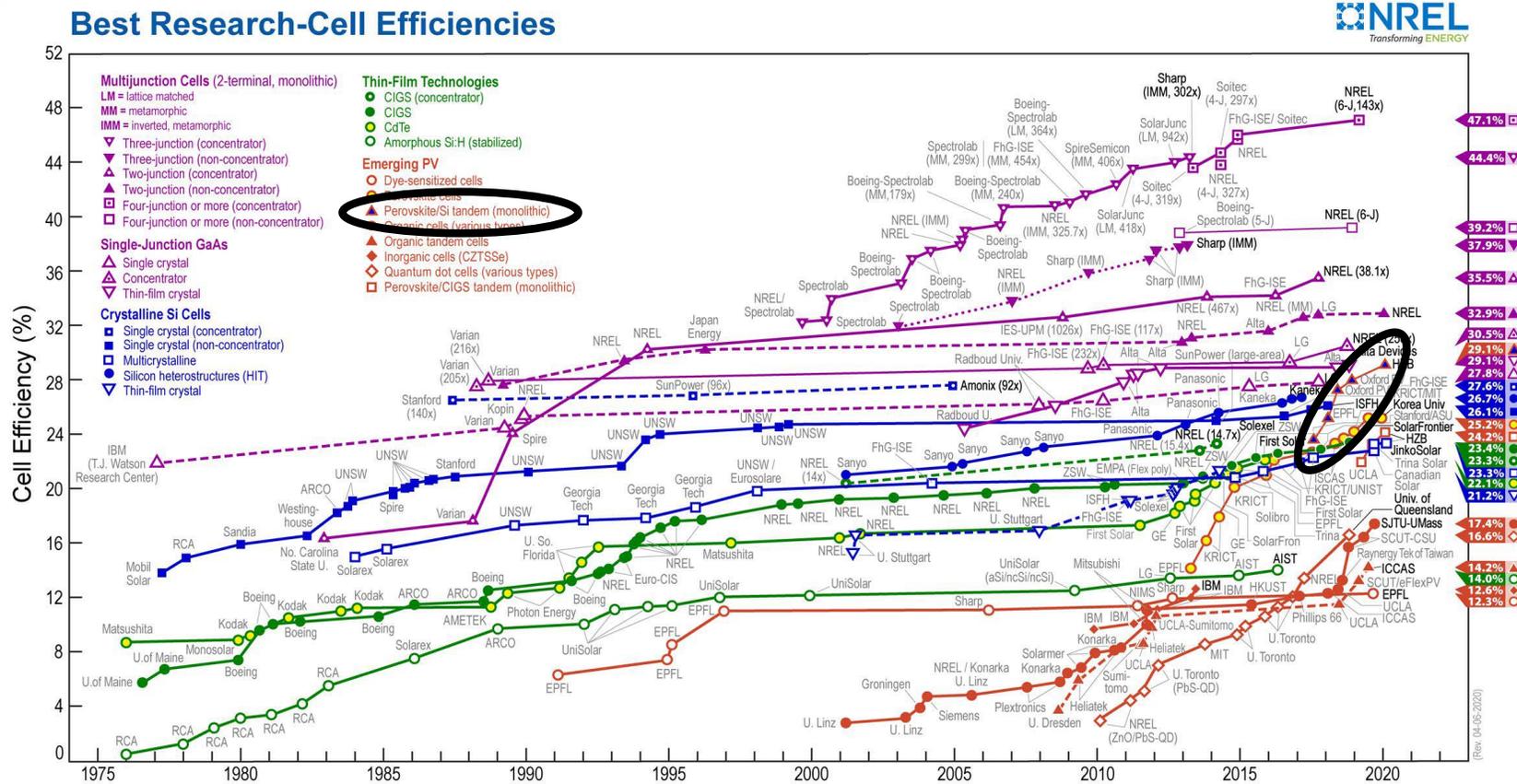
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Outline

- Motivation
- Co-sputtering
- Sequential sputtering
- Conclusions



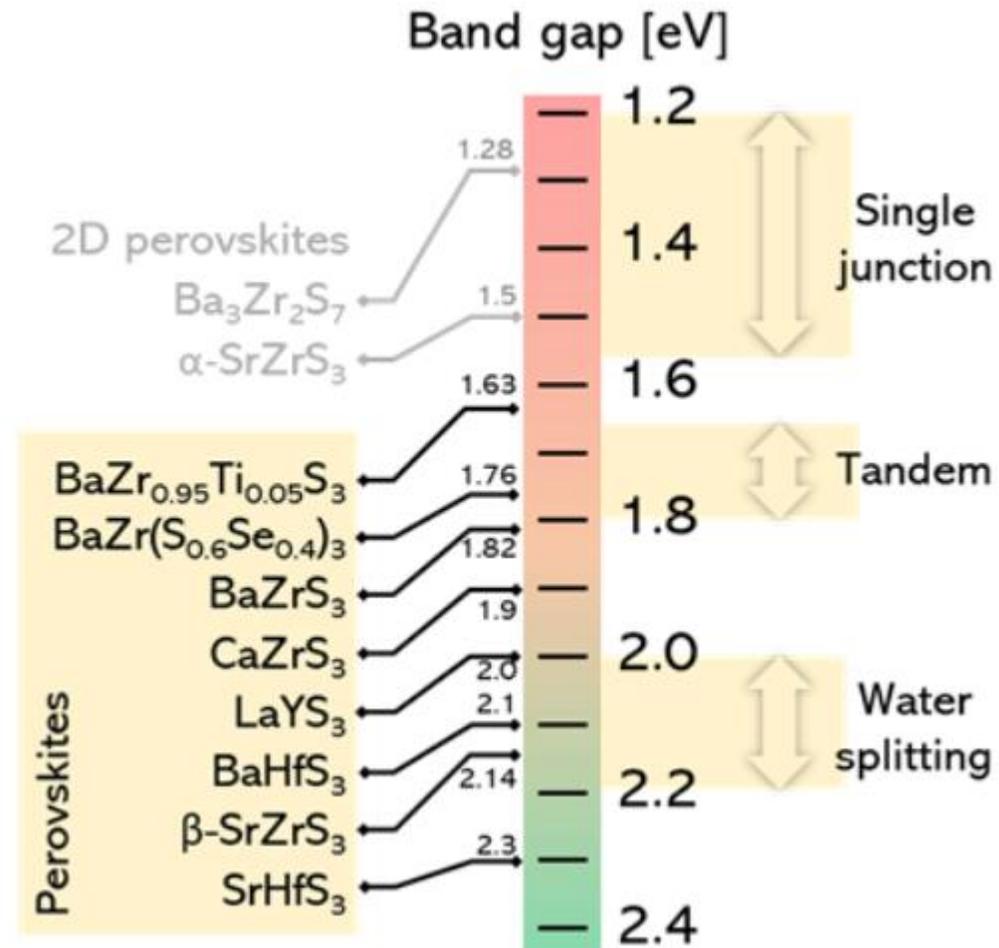




Concerns: toxicity (Pb) and stability

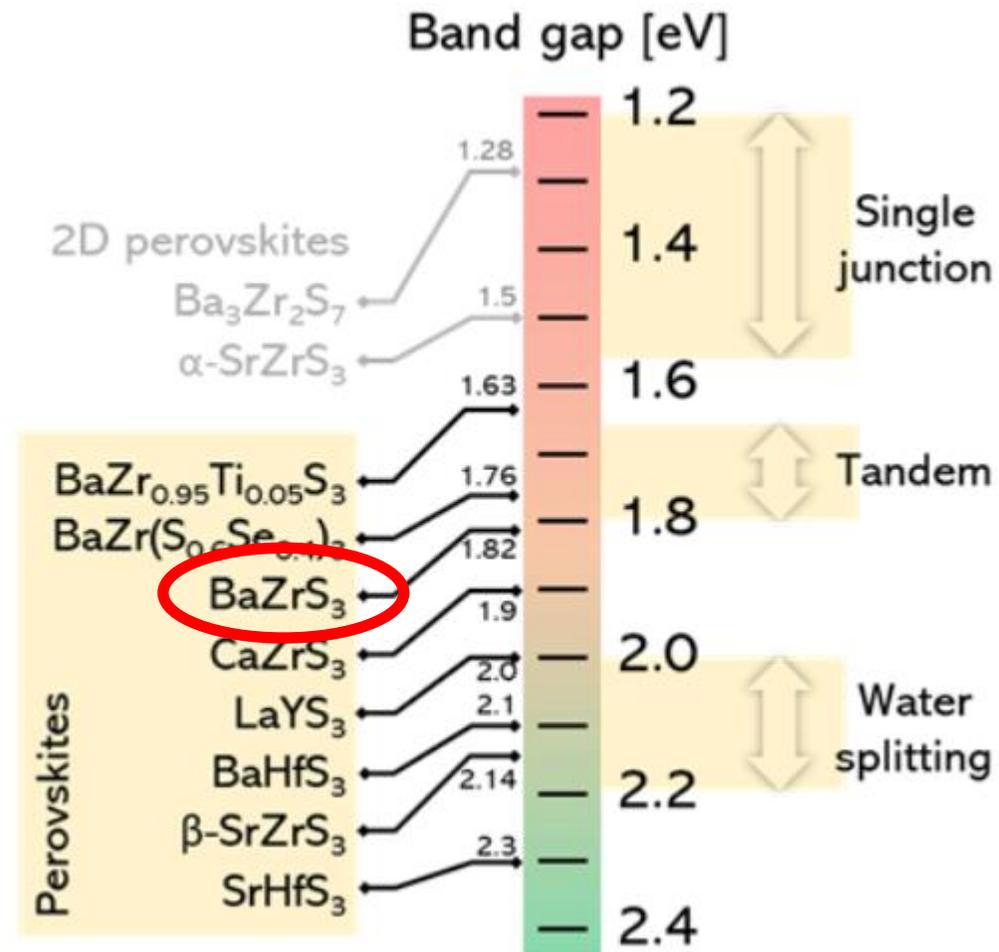


Chalcogenide Perovskites





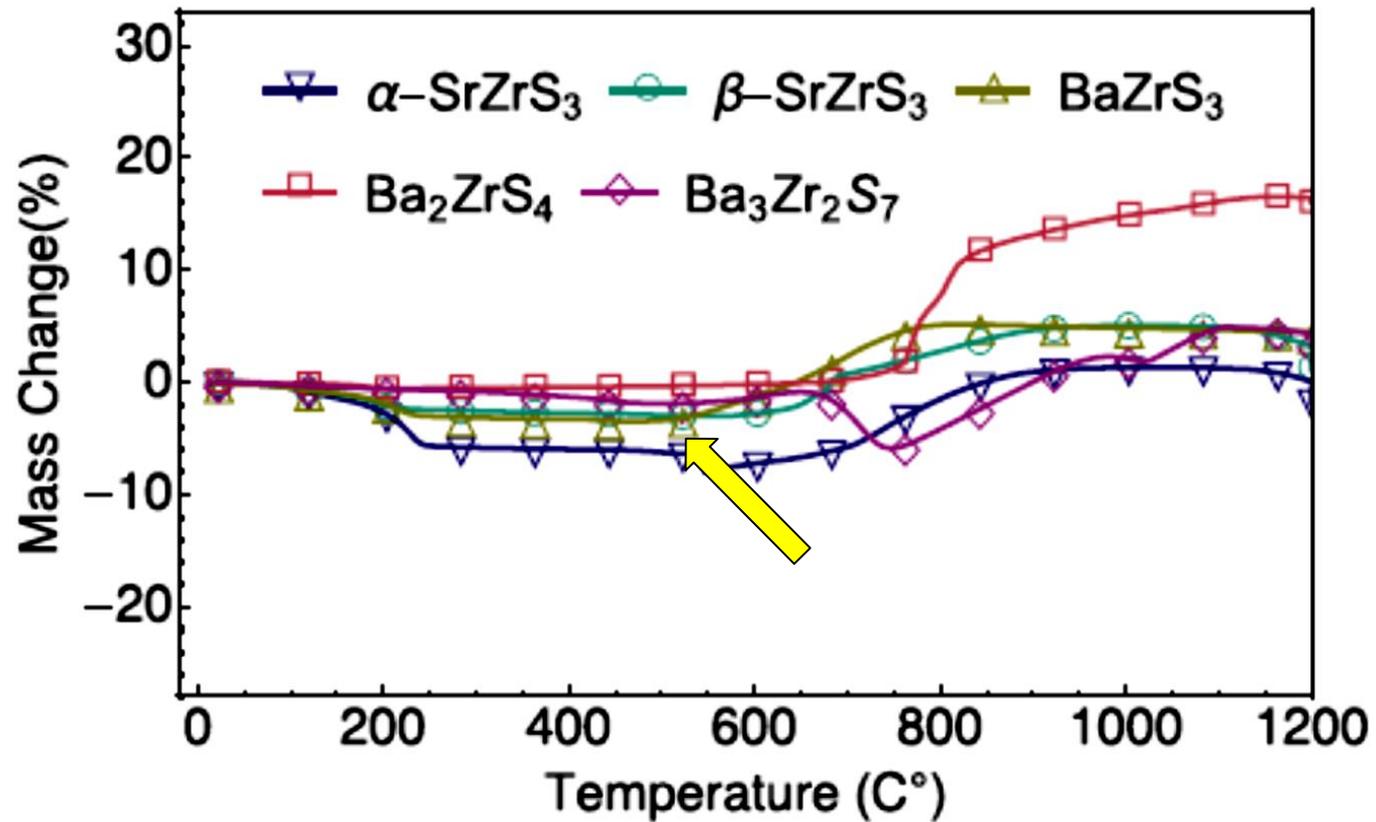
Chalcogenide Perovskites





BaZrS₃ - Stability

Heating in air - TGA



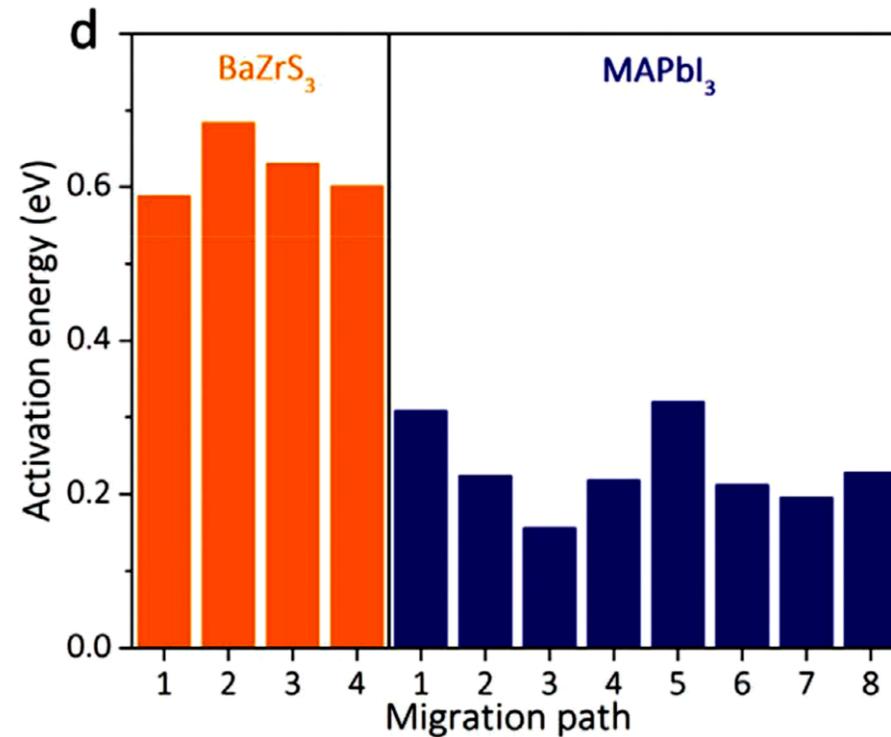
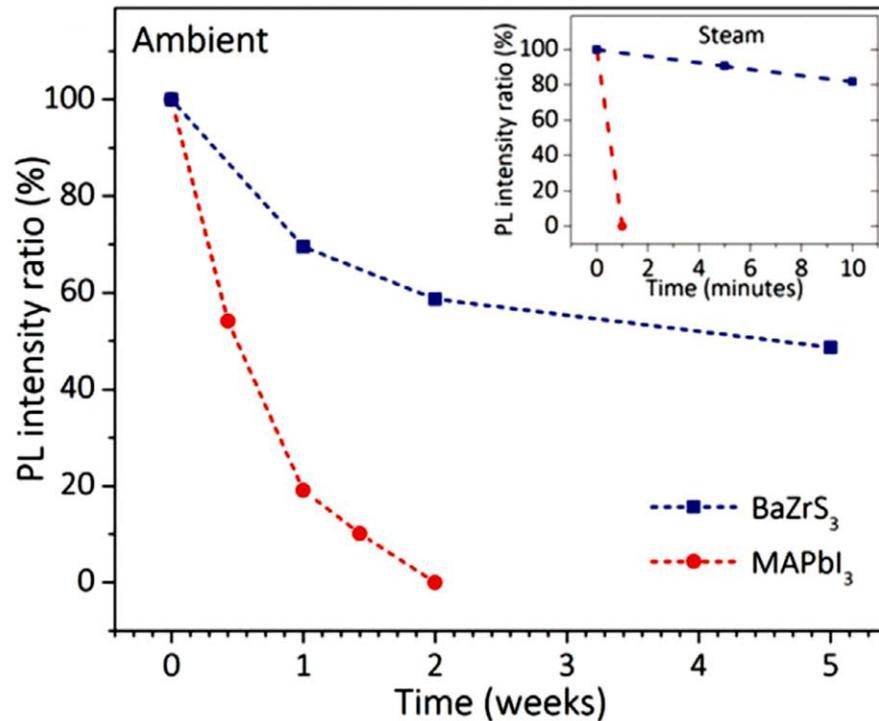
Niu S., *J. Mater. Res.*, Vol. 33, No. 24, 2018, pp. 4135-4143



BaZrS₃ - Stability

High energy barrier for anion diffusion → Reason for high stability?

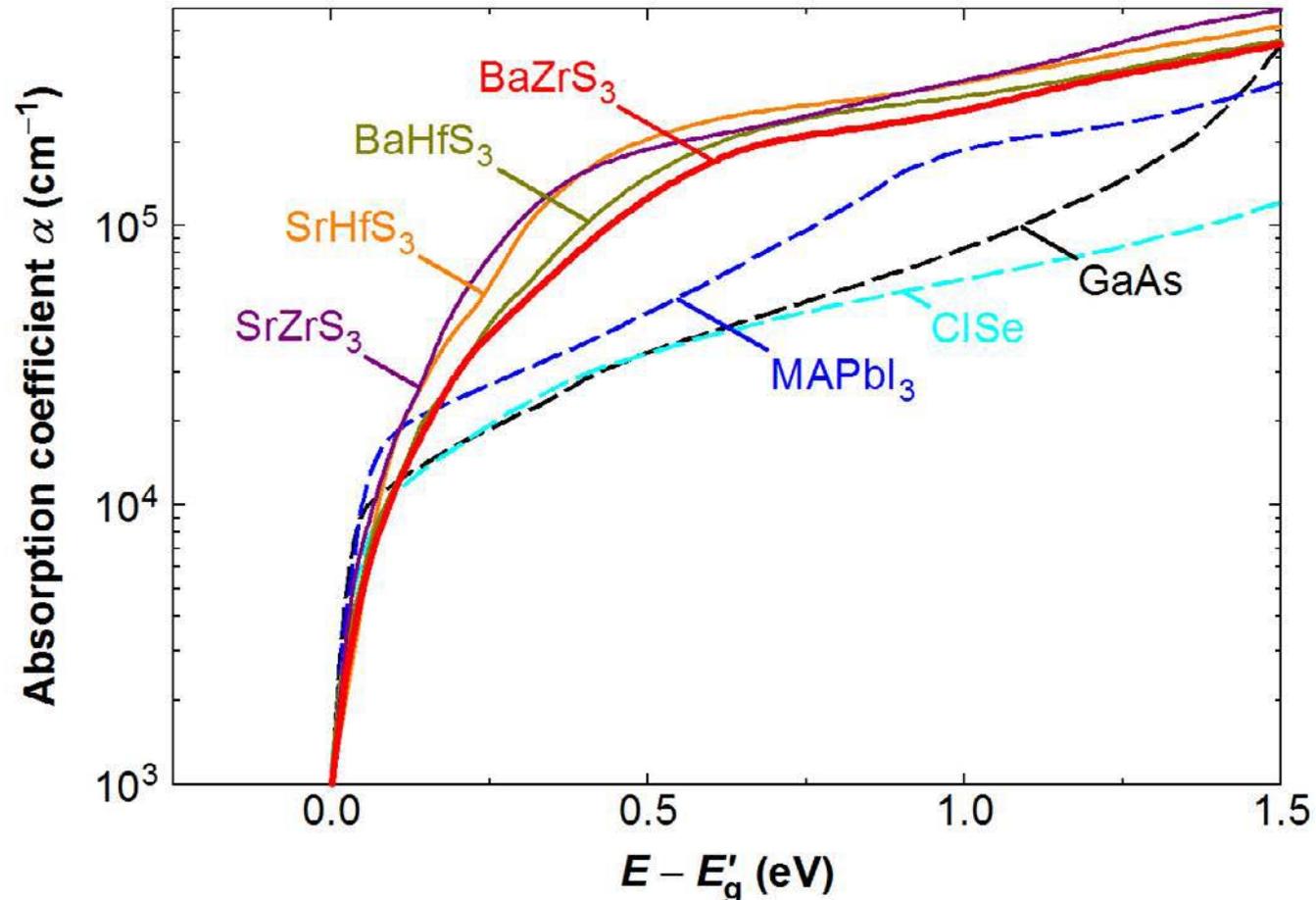
V_I migration rates in MAPbI₃ are about **seven orders of magnitude** higher than those of V_S in BaZrS₃





Strong Band-Edge Absorption

Nishigaki Y., *Sol. Rr.*, 1900555 (2020)



$\alpha > 10^5 \text{ cm}^{-1}$ near band edge

Highest among all known
solar absorber layers



Co-Sputtering

Deposition



1st step

RT

BaS target

Zr target

H₂S atmosphere

Amorphous film



Heating



2nd step

ex-situ in RTP

60 s

N atmosphere

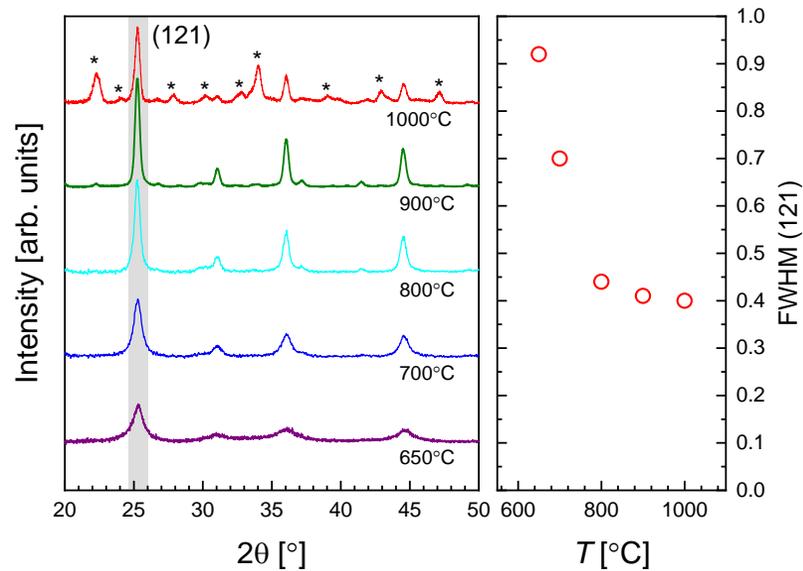
650 – 1000 °C

Crystalline film

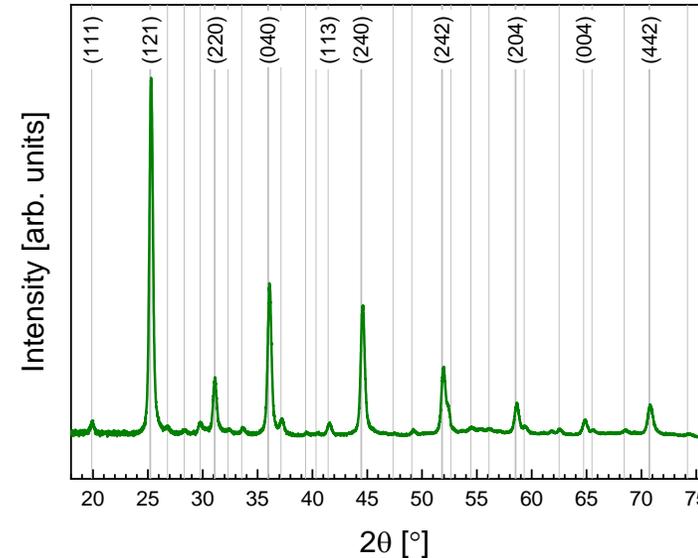
200 – 400 nm



X-Ray Diffraction



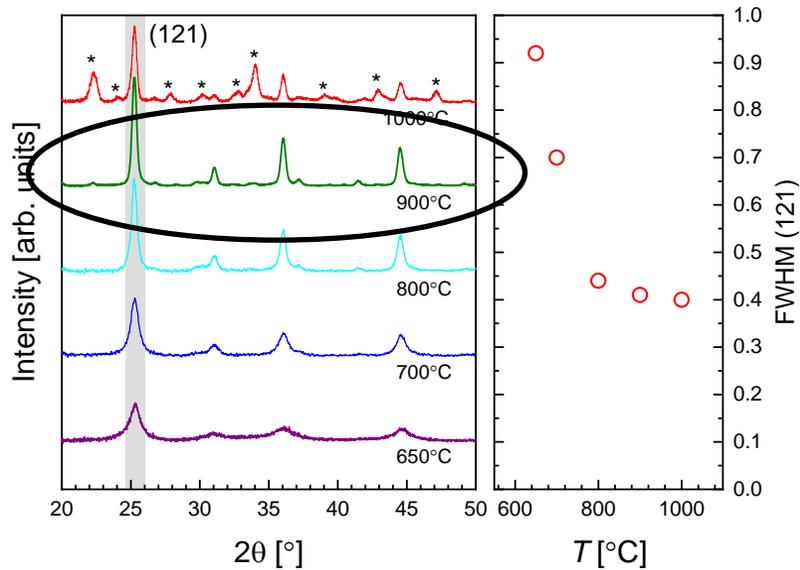
Clearfield A., *Acta Cryst.* (1963), 16, 134



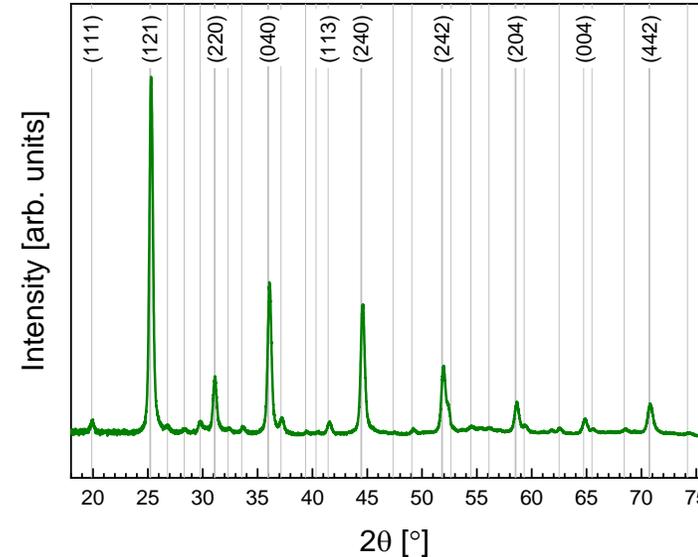
- XRD for each heating temperature
- Pattern quality improves with increasing temperature



X-Ray Diffraction



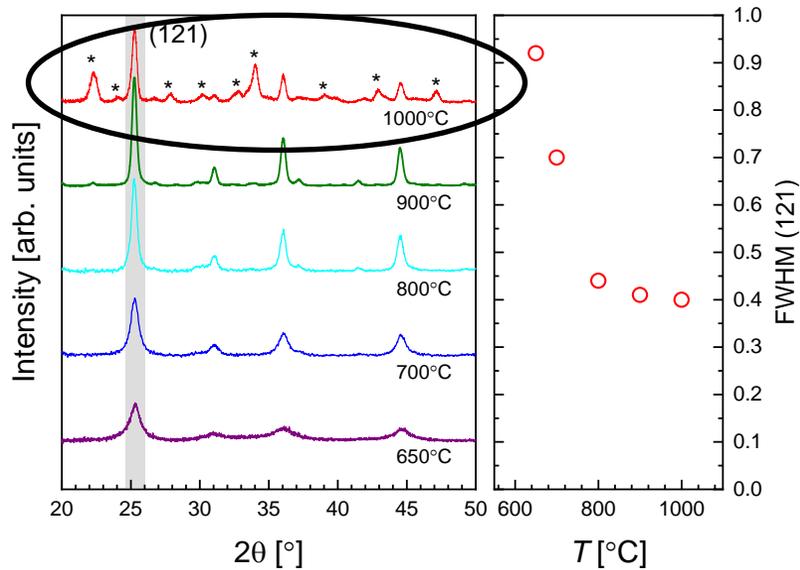
Clearfield A., *Acta Cryst.* (1963), 16, 134



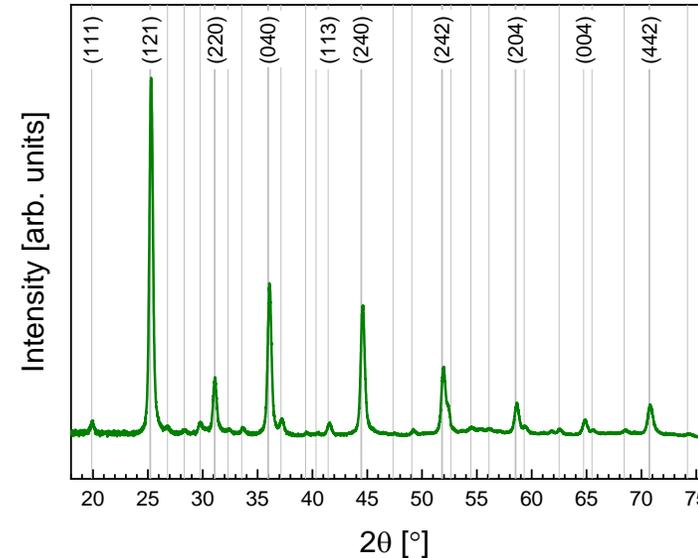
- Optimum temperature: 900 °C
- Perfect agreement with the reference pattern
- Dominant crystalline phase: BaZrS₃
- ZrO₂ in some cases



X-Ray Diffraction



Clearfield A., *Acta Cryst.* (1963), 16, 134

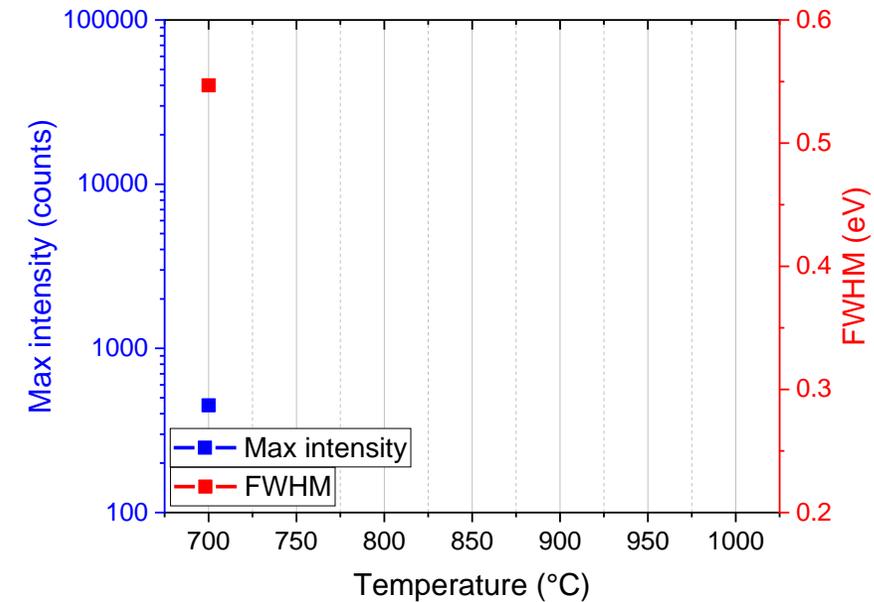
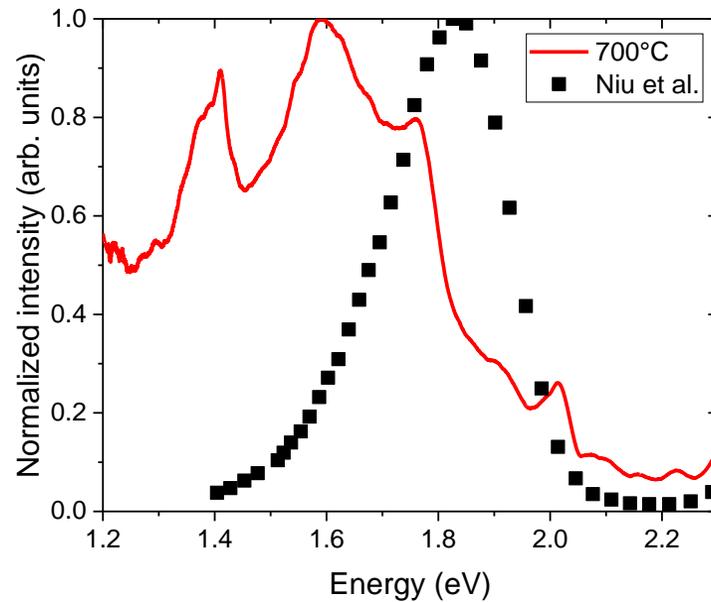


- Appearance of other phases at 1000 °C → Decomposition
- High thermal stability



Photolumuminescence

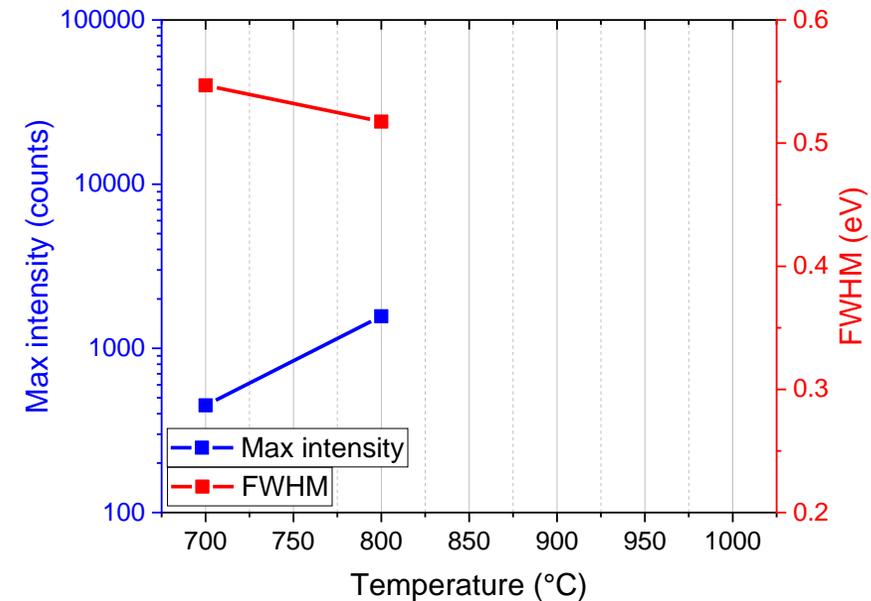
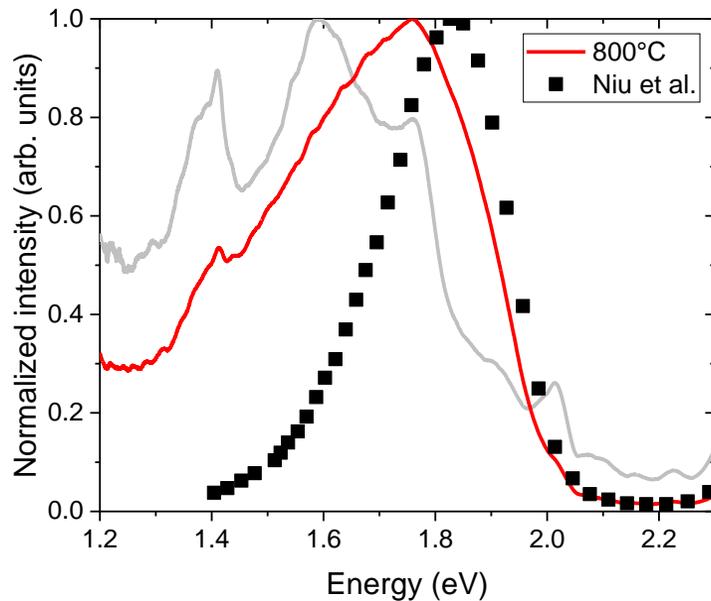
Reference from powders (60 h combustion)
Niu, S., *Adv. Mater.* 2017, 29 (9), 1604733





Photolumuminescence

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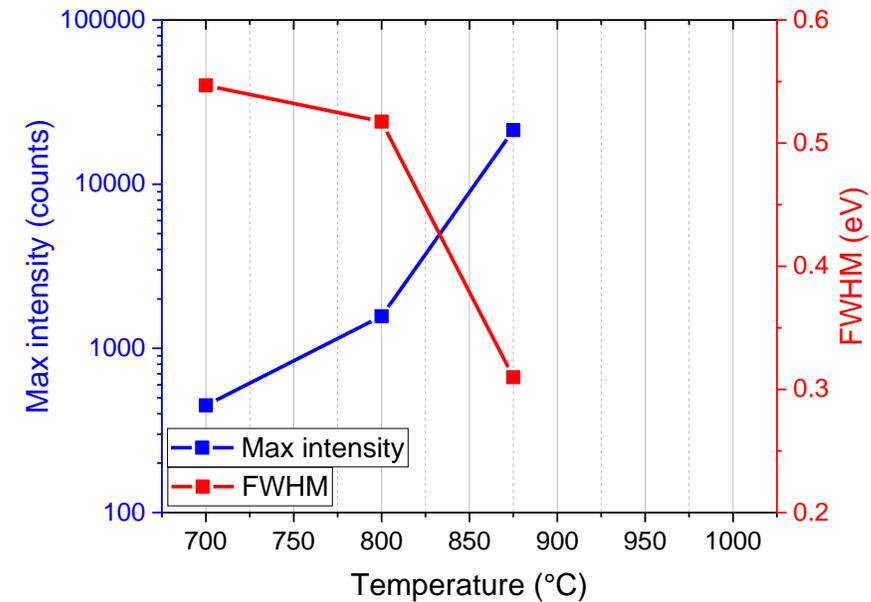
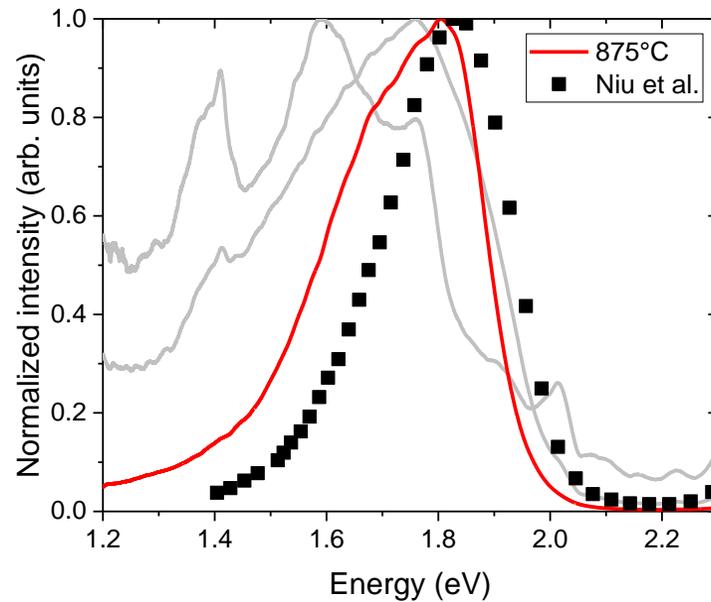


Main peak becomes narrower, higher, and moves towards higher energies



Photolumuminescence

Reference from powders (60 h combustion)
Niu, S., *Adv. Mater.* 2017, 29 (9), 1604733

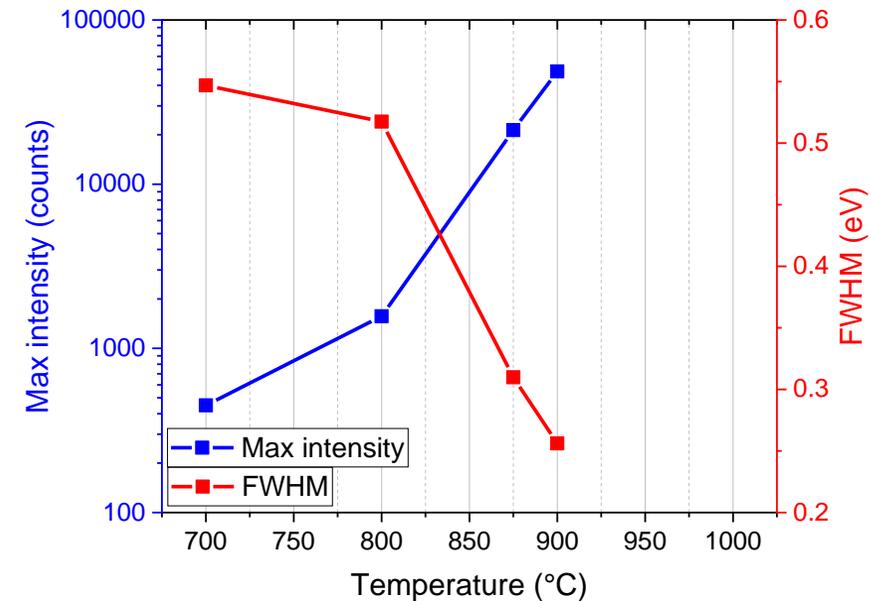
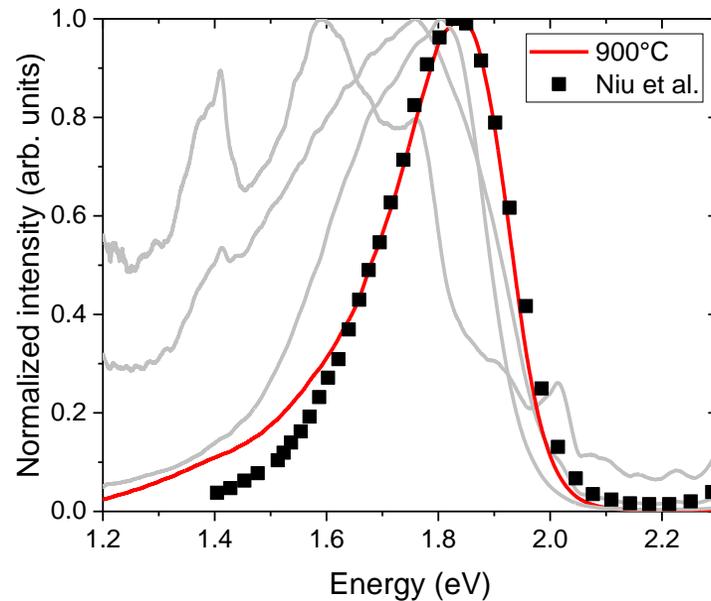


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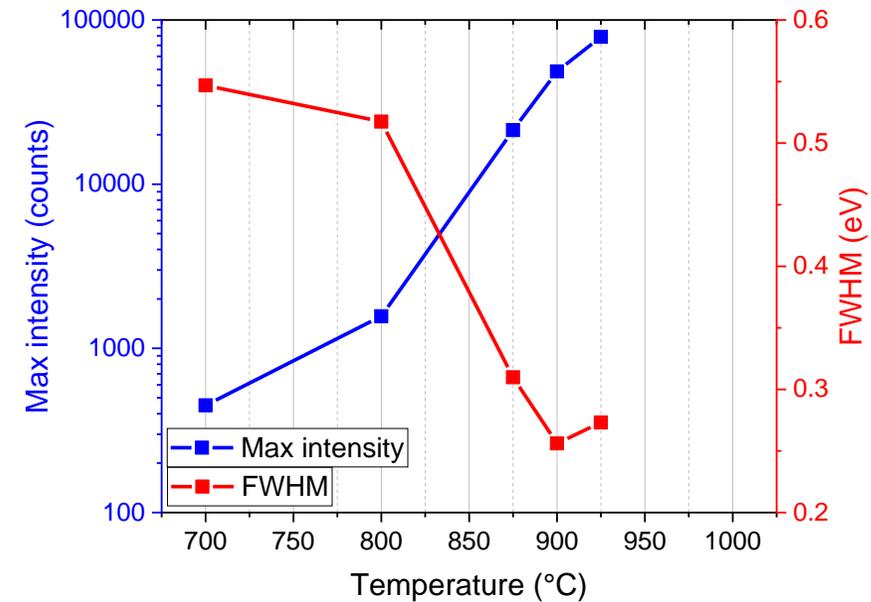
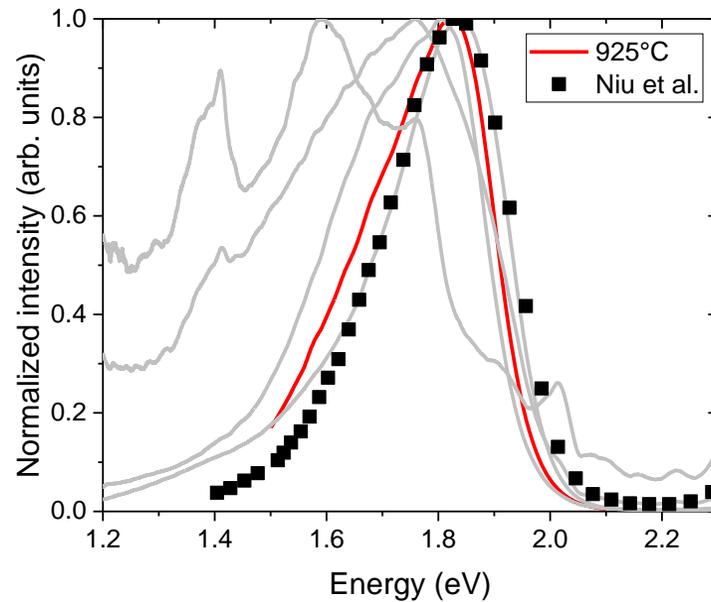


Good agreement with literature at 900 °C



Photolumuminescence

Reference from powders (60 h combustion)
Niu, S., *Adv. Mater.* 2017, 29 (9), 1604733

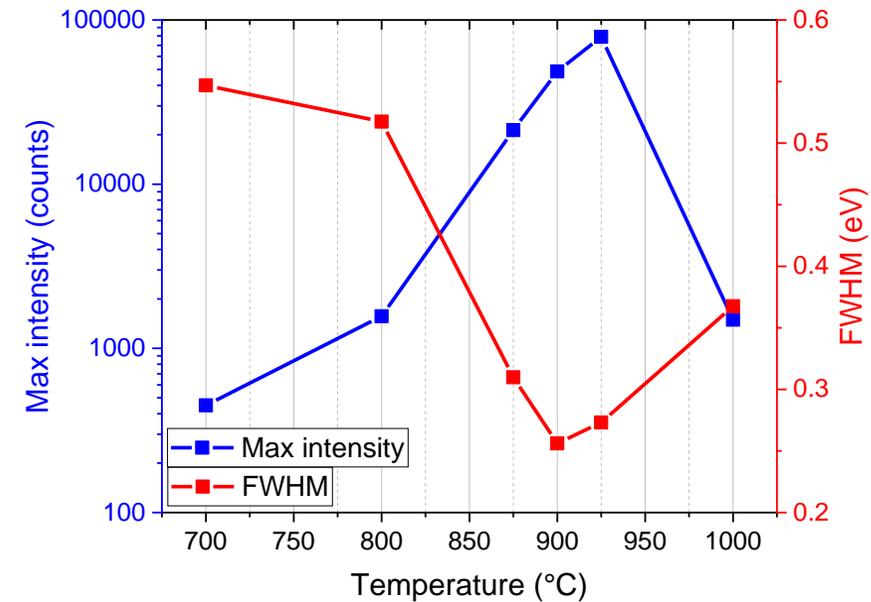
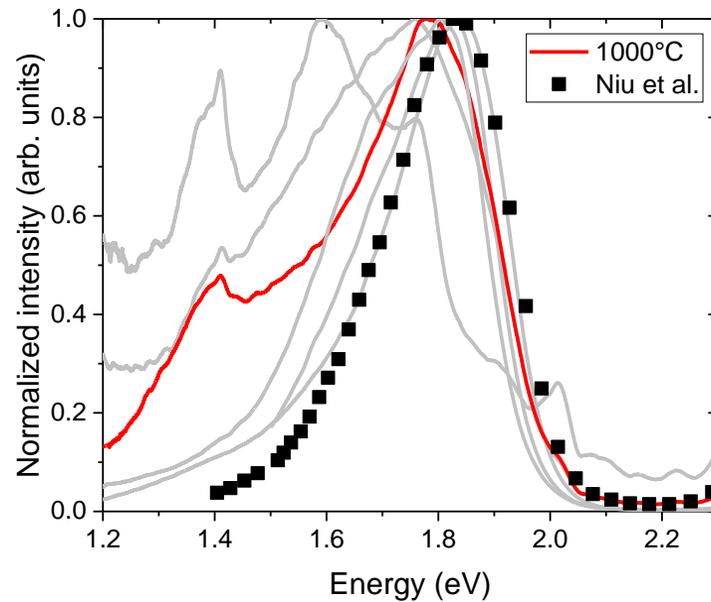


Reversed trend above 900 °C



Photolumuminescence

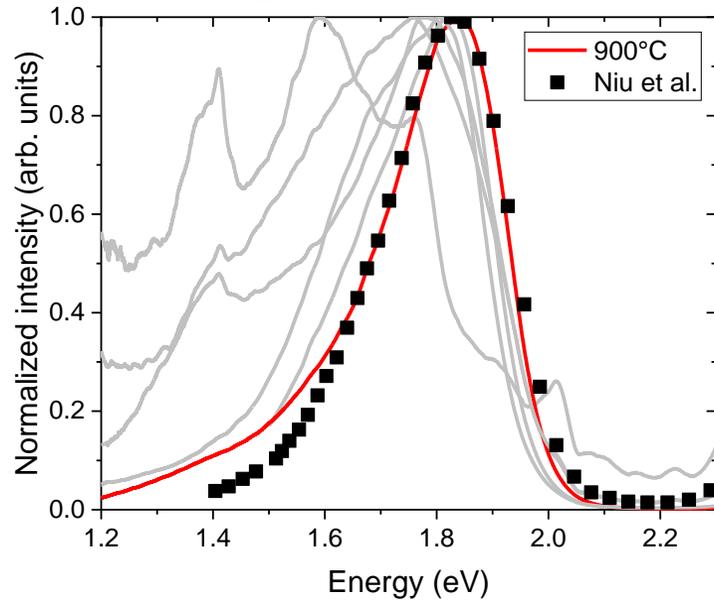
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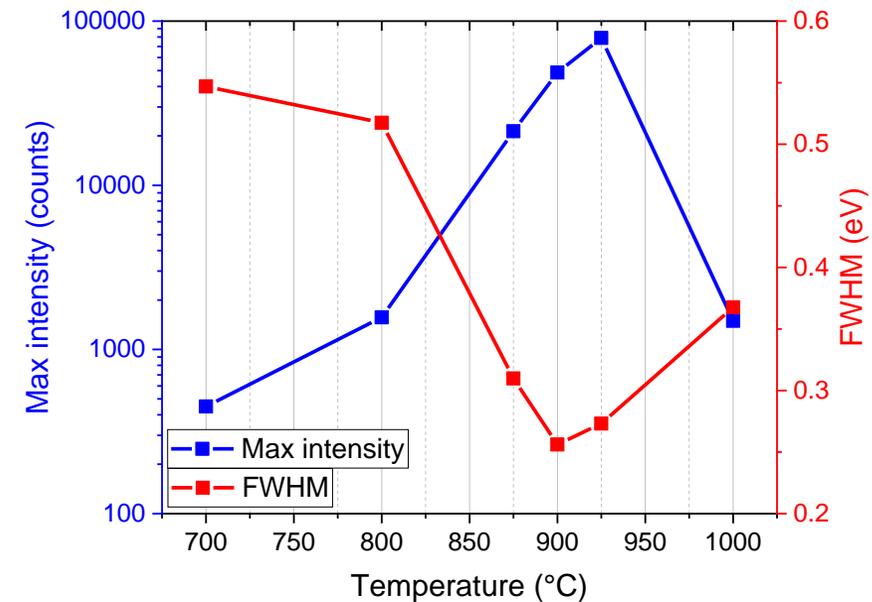
Reversed trend above 900 °C



Photoluminescence



- Best temperature in terms of PL: 900 °C (as for XRD)
- Bandgap: ~ 1.84 eV \rightarrow Tandem cells
- Quality comparable with the reference from powders (60 h combustion)



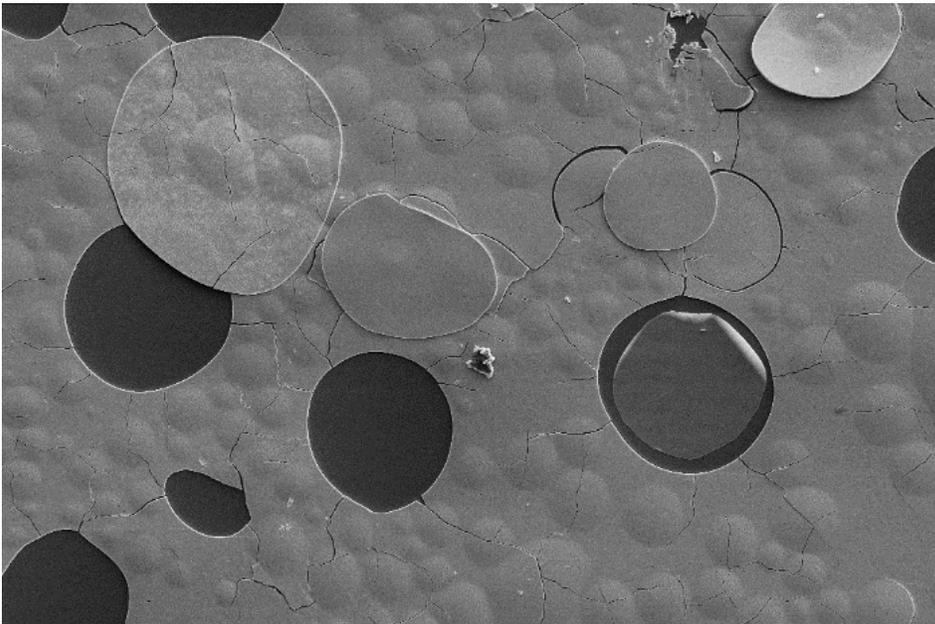
Comparotto C. et al.,
ACS Appl. Energy Mater. 2020, 3, 3, 2762–2770



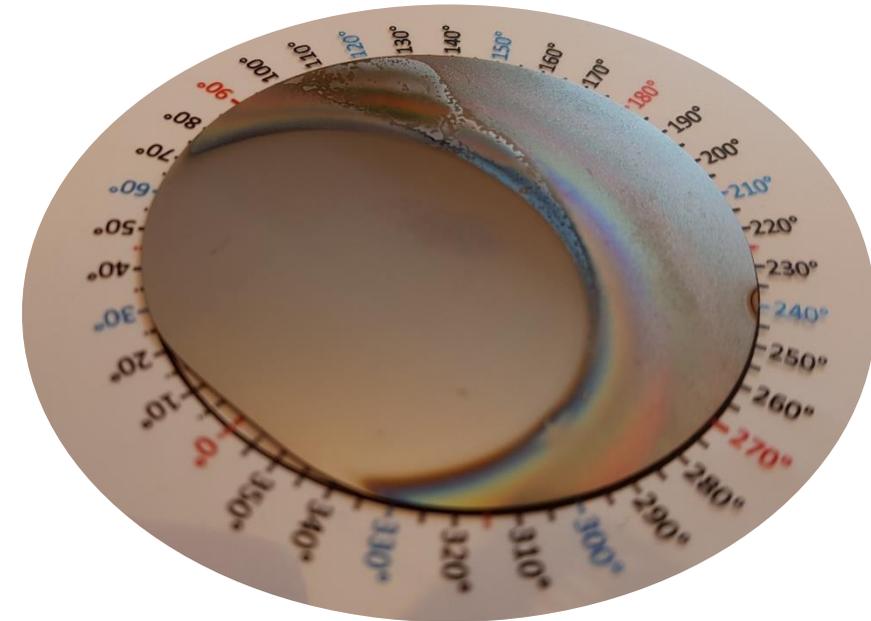
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Morphology

Microscopic: Stress, Adhesion



Macroscopic: Resputtering



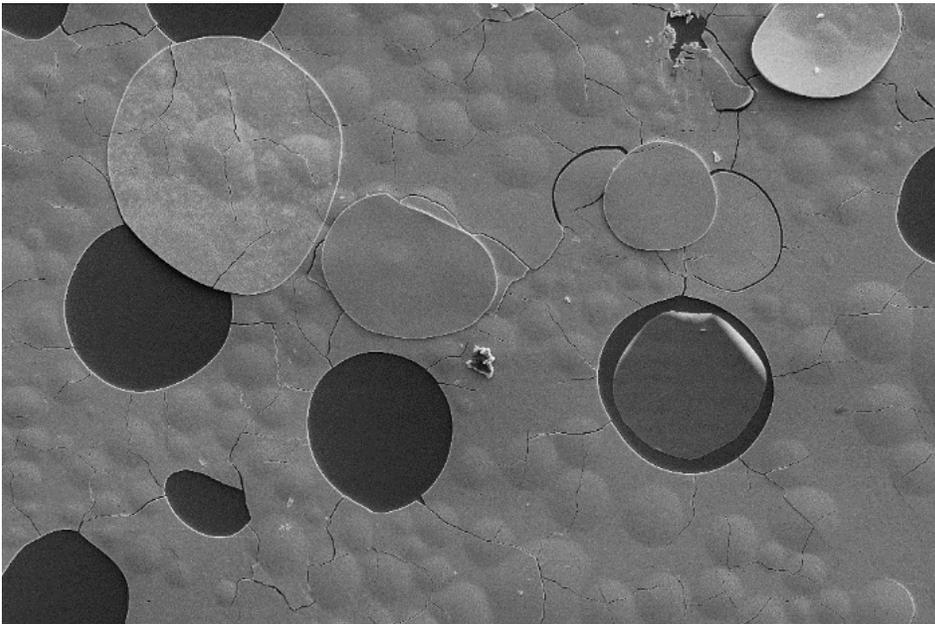
- Limited range of flows, power, and pressure in current sputtering system
- Explore new sputtering route



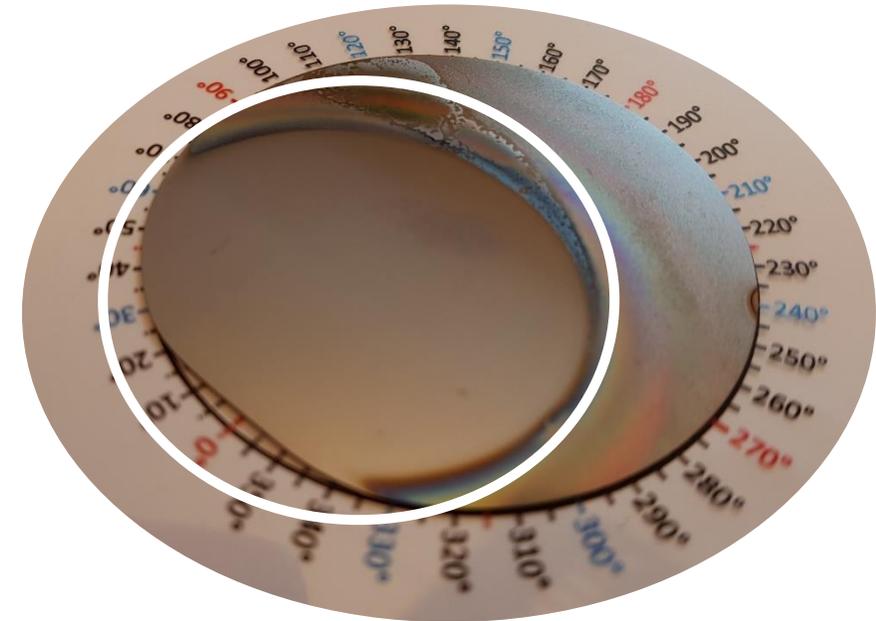
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Morphology

Microscopic: Stress, Adhesion



Macroscopic: Resputtering



- Limited range of flows, power, and pressure in current sputtering system
- Explore new sputtering route



Co-Sputtering

Co-sputtering



ex-situ heating in RTP
60 s
900 °C





Sequential sputtering

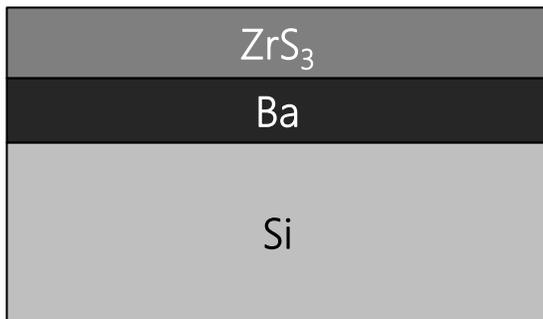
Co-sputtering



ex-situ heating in RTP
60 s
900 °C



Sequential sputtering

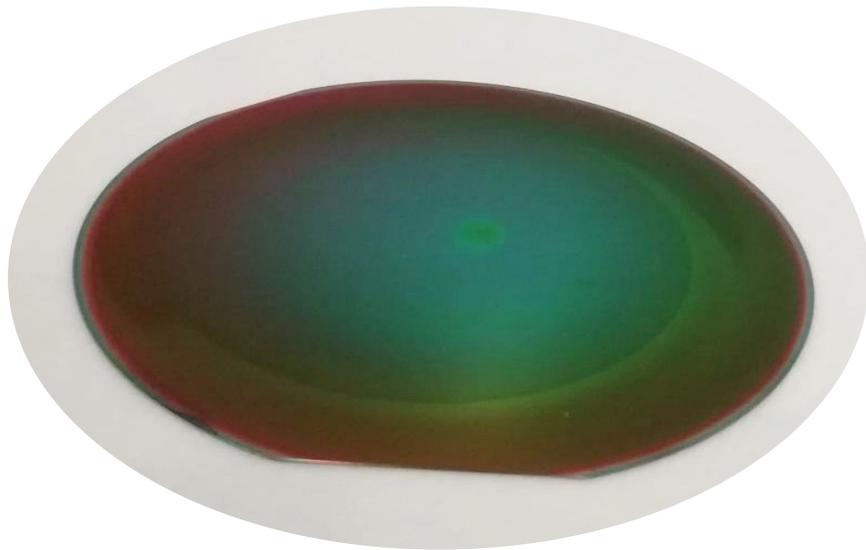


in-situ heating
~ 1 h
~ 700 °C





Homogeneous deposition



Co-sputtering

$\text{BaS} + \text{H}_2\text{S} \rightarrow \text{Resputtering}$

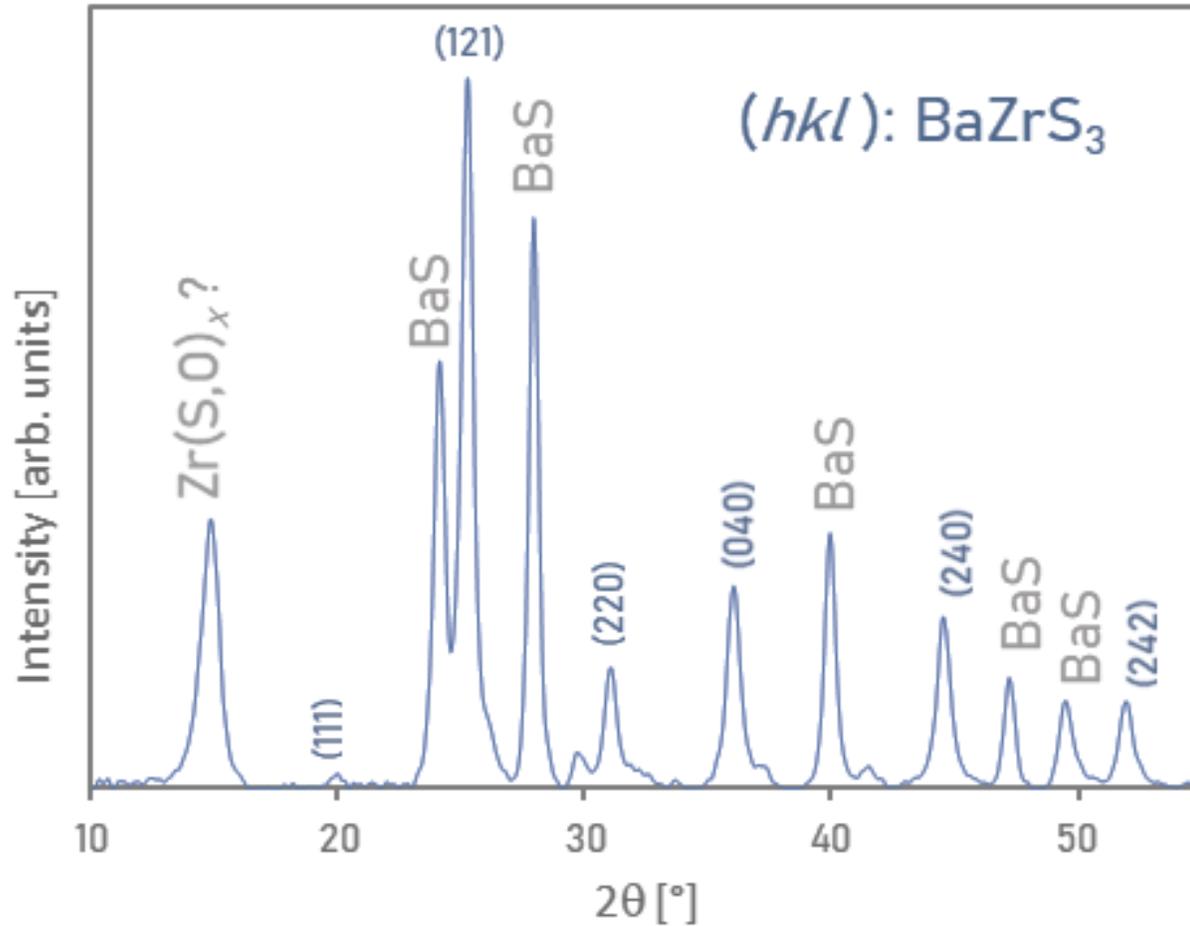
Sequential sputtering

$\text{Ba} + \text{Ar} \rightarrow \text{No resputtering}$

➤ Negative S ions?



X-Ray Diffraction



Presence of:

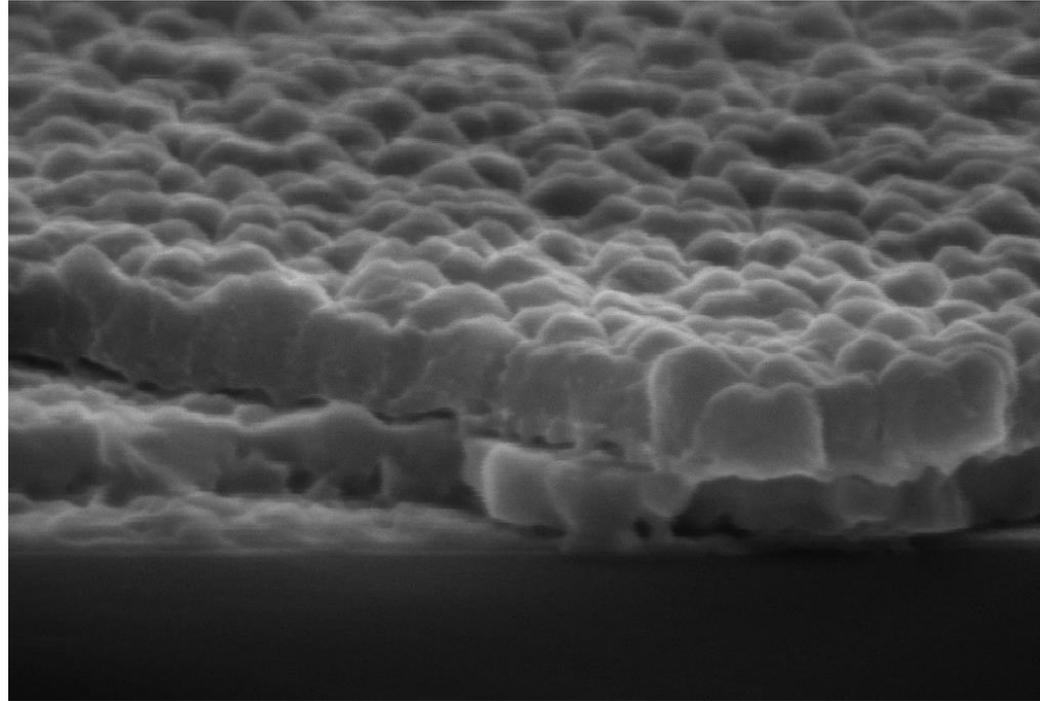
- BaZrS₃
- BaS
- Zr(S,O)?



Ion Beam Analysis



BaS + impurities



Layer	Ba (at%)	Zr (at%)	S (at%)	O (at%)
Top	19	20	50	10
Bottom	44	2	39	10
Stoichiometric BaZrS ₃	20	20	60	0



Conclusions

- BaZrS₃ possesses the right properties for perovskite/Si tandem cells → Thin films
- **Co-sputtering**
 - Fabrication of BaZrS₃ thin films of good crystalline quality
 - Inhomogeneity
 - High formation temperature (900 °C)
- **Sequential sputtering** (very recent)
 - Homogeneous film
 - Formation of a BaZrO_{0.15}S_{0.85} film at ~ 700 °C
 - Sluggish reaction → Need of relatively high temperature (e.g. compared to other chalcogenides)
 - High thermal stability



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Acknowledgements



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STandUP *for* **ENERGY**

Thank you for your attention!